RADICAL PLASMA SOURCE (REMOTE PLASMA SOURCE) - MA2000C-823BB

Categories: Plasma components

ADDITIONAL INFORMATION

Typ	Radical plasma source (Remote Plasma Source)
Process	Etching & Deposition
Output Connection Type	
Dielectric material	Sapphire
Mains voltage nominal [V]	230 / 208
Output Power CW [W]	2000
Frequency [MHz]	2450

Muegge GmbH
Hochstrasse 4-6
64385 Reichelsheim
Germany

T. +49 (0)6164-9307-0
F. +49 (0)6164-9307-93
E. info@muegge.de
www.muegge.de